

From Wafers to Modules to Mass Production: Solving All Bottlenecks in Silicon Heterojunction Technology

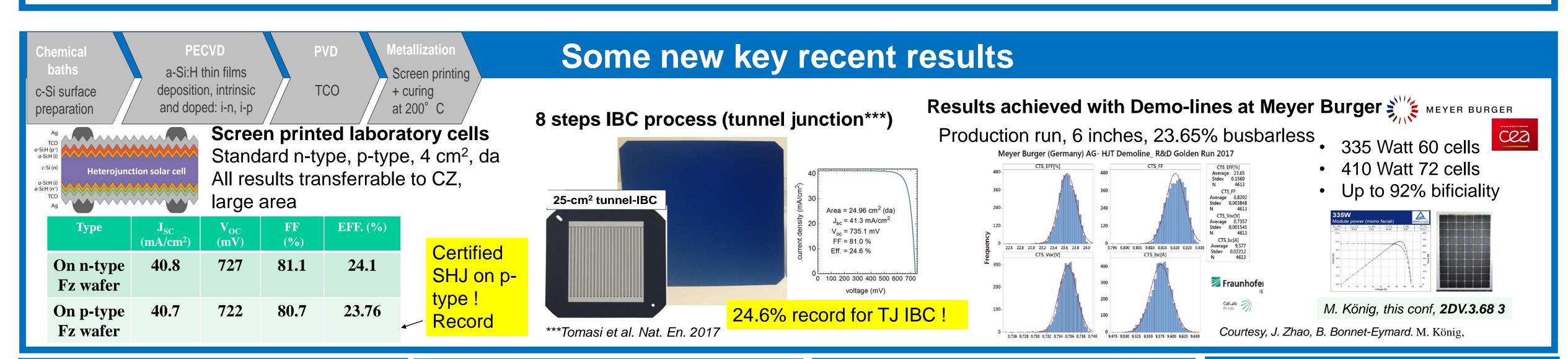


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Removing all obstacles to massive market penetration

Silicon heterojunction solar cells have less manufacturing steps and have allowed achieving higher efficiency than PERC cells. However the market has been slow in taking up the technology. Here we show some of the obstacles that have been overcome in the last 10 years which make the technology more ready than ever for a mass market launch.

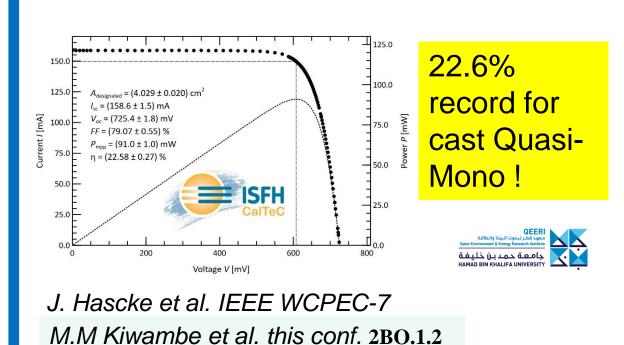


Impossible to get good quality low cost n-type wafer

- Strong material improvements over the last 10 years
- Today SOA n-type c-Si does not require gettering or thermal donor killing
- At 180 μm thickness n-type wafer 5% more expensive than p-type (less pulls)
- -1.5cts per 10μm less...
- N-type 140 μm wafers are cheaper than 170 μm for standard cells

High Quality n-type wafer at lower cost than p-type wafer by using 30 µm less giving you more Watts

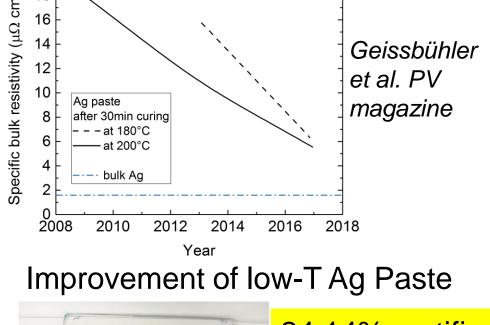
- Suitable for almost all materials
- For QuasiMono and multi, gettering/hydrogenation might be required



No good metallization solutions available, 500 mg of Ag per cell

- Strong improvements of low T Ag paste. ρ now down to 5 $\mu\Omega$ cm.
- Possibility to plate cells, or to shingle
- Solutions with multi-wire
- Solutions with multi-bus bars

Certified metallization and interconnection with no expensive materials available



24.14% certified plated cell on 225 cm², 4 busbars

Precursors from CHOSHU

A. Lachowicz, this conf. 2CO.12.5



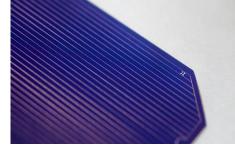
Indium-free smart Wire, with as little as 25 mg Ag per side

Complex manufacturing processes. Solar cell makers do not use // polate PECVD and PVD tools

- From thin film solar, flat panel displays and glass coating, low cost per m² from PECVD (e.g. parallel plate reactor) and PVD.
- Fewest number of process steps:
 5-7 depending on tools and processes
- Alternative deposition techniques available (hot wire, TCO by PAE)
- Easily controlled homogeneity with good tool design
- > 20 research institutes and (pilot) lines with above 22% efficiency

Fully controlled. Good tools will make in one day >> 20% cells





CSEM/EPFL SILICON
HETEROJUNCTION
R&D PLATFORM
> 20 tools for advanced
and fast R&D

Too expensive industrial productions solutions, reliability issues

- Equipments price going down with competition
- Even extra capex 5 M\$/100 MW
 → only 0.8 cts/W extra
- Higher capex, compensated by efficiency/bificiality/energy yield
- When designed properly, ultraresistant products, no PID.
- Can even improve under light soaking!

 J.Cattin, this conf. 2DO.1.4.

Production equipment available allowing competitive costs for manufacturing at GW level

- Now close to 10 lines with
 > 100 MW capacity
- Several GW announced
- Need of volume as with all c-Si technologies



Exemple: Helia Meyer Burger platform for SHJ

Cost of electricity

- Low temperature coefficient (-0.2%/°C to -0.27%/°C)
- No PID
- High bifaciliality
- → Higest energy yield and lowest LCOE
- A. Richter et al. IEEE WCPEC-7



JZOSnú
Ceso
LiF
Per
Spi
nc-s
nc-s
a-S
a-S
a-S
TTO
Ag

F. Sahli et al Nat.

IEEE WCPEC-7

Transform to IBC with 5-8% rel. Eff. increase

Nove to multijunction

Ferovskite
Spiro-TTB
no-Si:H(n+)
no-Si:H(n+)
a-Si:H(n)
a-Si:H(n)
c-Si

Transform to IBC with 5-8% rel. Eff. increase
III-V/Si (35.9%**)
Perovskite tandem
devices

Upside potential

25.2 % certified record for PK/Si textured

**Essig et al. Nat. En. 2017

conclusion

Over the last 10 years, improvements in:

- Processes compatible with industrial production,
- Efficiency achieved on production tool,
- Metalization and interconnections, reliability,
- Material quality,
- Tools for cost-effective production.

If/when capital is available, Si heterojunction technology is ready for true mass market launch

Read more: Jan Haschke et al., Solmat 187 (2018), 140





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